

CLAIMS:

1-17 (canceled)

18. (original) A wafer defining a plurality of MEMS devices attached together comprising:

at least two features of said MEMS devices separated by first lines etched completely through said wafer, said first line having at least a first selected width;

second lines etched part way through said wafer defining individual ones of said plurality of MEMS devices, said second lines having a second width which is less than said first selected width.

19. (original) The wafer of Claim 18 wherein said width of said first lines have a ratio greater than 4:1 with respect to said width of said second lines.

20. (original) The wafer of Claim 18 wherein said first selected width is at least about 50 μ m and said second width is about 10 μ m.

21. (original) A wafer defining a plurality of gimbal mirror devices attached together comprising:

at least two features of said gimbal mirror devices separated by first lines etched completely through said wafer, said first lines having at least a first selected width;

second lines etched part way through said wafer defining individual ones of said plurality of gimbal mirror devices, said second lines having a second width which is less than said first selected width.